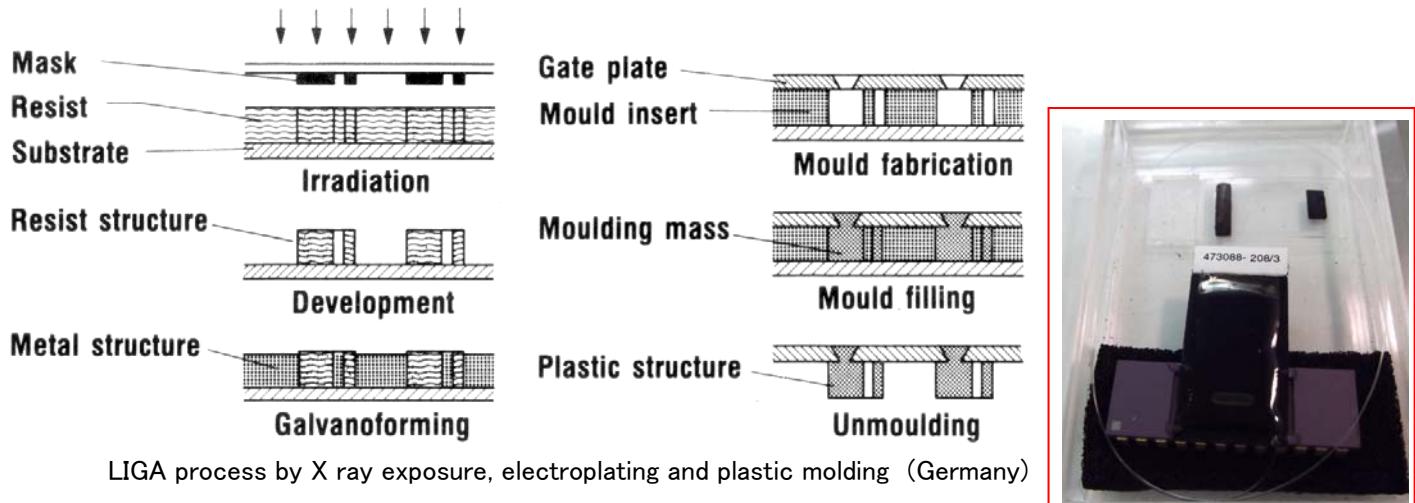
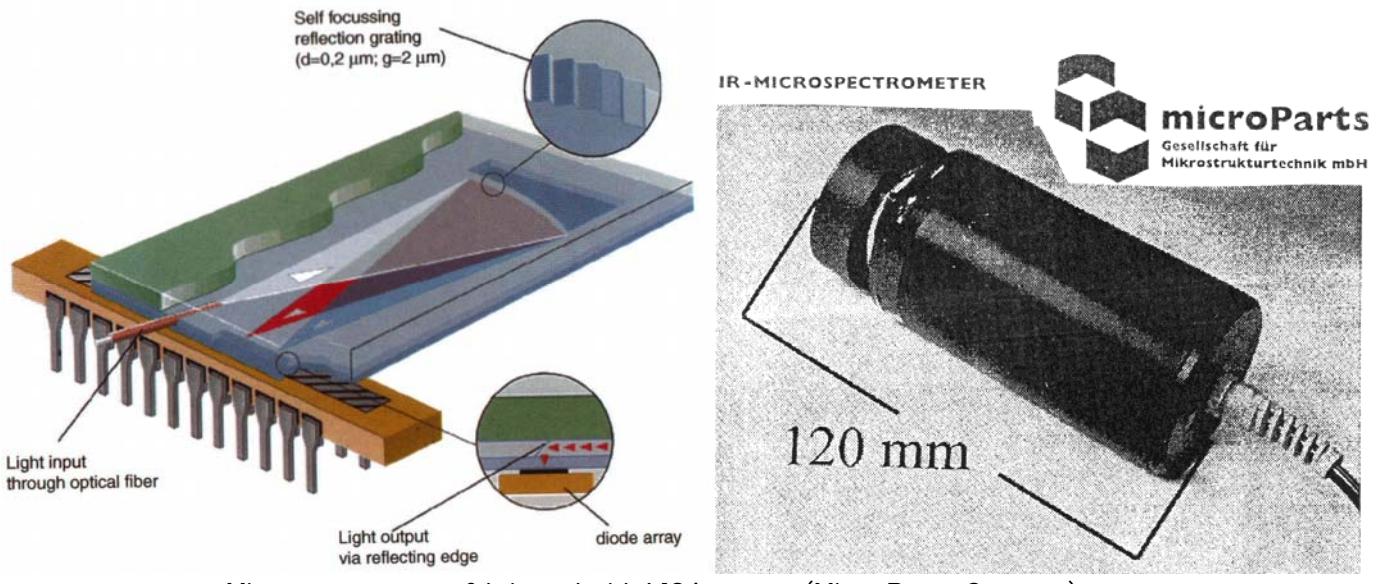


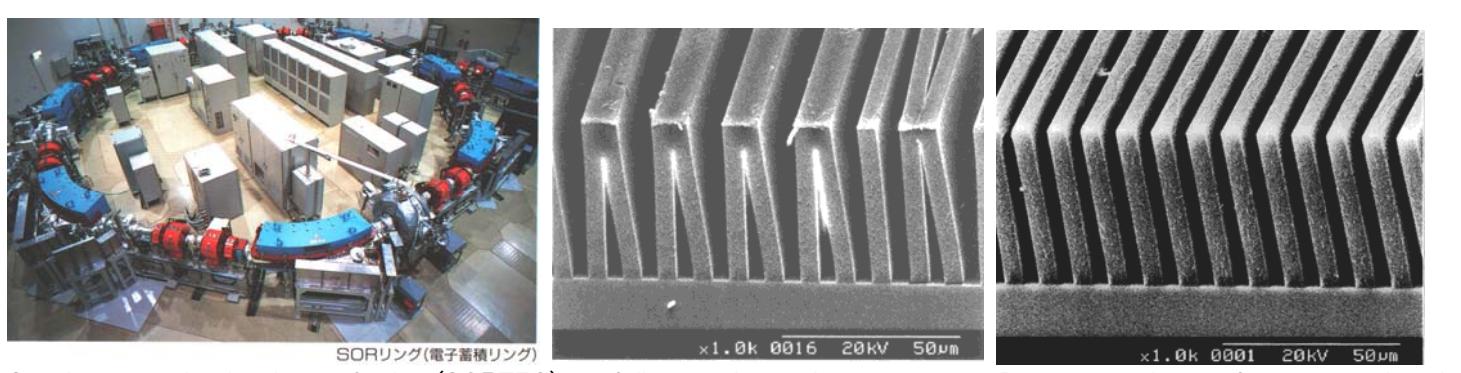
LIGA Process



Reference : E.W.Becker, W.Ehrfeld, P.Hagmann, A.Maner and D.Munchmeyer, Fabrication of Microstructures with High Aspect Ratios and Great Structural Heights by Synchrotron Radiation Lithography, Galvanoforming, and Plastic Moulding (LIGA Process), Microelectronic Engineering, 4 (1986) pp.35–56



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Synchrotron orbital radiation facility (SORTEC) Adhesion during drying Drying using low surface tension liquid

LIGA process using negative resist (THB-N1 (JSR) Ltd.) (Tohoku Univ. – SORTEC)

Reference : S.Watanabe, M.Esashi and Y.Yamashita, Fabrication Methods for High Aspect Ratio Microstructures, J.of Intelligent Material Systems and Structures, 8 (1997) pp.173–176